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INFORMATION DISCLOSURE STATEMENT BY APPLICANT

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Sheet 1 of 1

Complete if Known

Application Number	TBA
Filing Date	December 6, 2001
First Named Inventor	Hatakeyama et al.
Group Art Unit	TBA
Examiner Name	TBA
Attorney Docket Number	KOJIM-440

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U.S. PATENT DOCUMENTS

Examiner Initials *	Cite No. ¹	U.S. Patent Document		Name of Patentee or Applicant of Cited Document	Date of Publication of Cited Document MM-DD-YYYY	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		Number	Kind Code ² (if known)			
S. J. L.	A	4,491,628		Ito et al.	01/01/1985	
	B	5,310,619		Crivello et al.	05/10/1994	
	C	5,580,695		Murata et al.	12/03/1996	
	D	5,609,989		Bantu et al.	03/11/97	

FOREIGN PATENT DOCUMENTS

Examiner Initials *	Cite No. ¹	Foreign Patent Document			Name of Patentee or Applicant of Cited Document	Date of Publication of Cited Document MM-DD-YYYY	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear	T ₆
		Office ³	Number ⁴	Kind Code ⁵ (if known)				
S. J. L.	E	JP	90027660	B	Frechet et al.	06/19/1990		
	F	JP	63027829	A	Crivello et al.	02/05/1988		
	G	WO	9837458	A1	Sone et al.	08/27/1998		
	H	JP	63149640	A		06/22/1988		
	I	JP	5113666	A		05/07/1993		
	J	JP	5232706	A	Kobayashi et al.	09/10/1993		
	K	JP	5249683	A	Kobayashi et al.	09/28/1993		

OTHER PRIOR ART -- NON PATENT LITERATURE DOCUMENTS

Examiner Initials *	Cite No. ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T ²
S. J. L.	L	Hinsberg et al., "Fundamental Studies of Airborne Chemical Contamination of Chemically Amplified Resists," <i>Journal of Photopolymer Science and Technology</i> , Vol. 6, No. 4 (1993) pp 535-546.	
	M	Kumada, et al., "Study on Over-Top Coating of Positive Chemical Amplification Resists for KrF Excimer Laser Lithography," <i>Journal of Photopolymer Science and Technology</i> , Vol. 6, No. 4 (1993) pp 571-574.	
	N	Hatakeyama, et al., "Investigation of Discrimination Enhancement with New Modeling for Poly-hydroxystyrene Positive Resists," <i>Journal of Photopolymer Science and Technology</i> , Vol. 13, No. 4 (2000) pp 519-524.	

Examiner Signature

Sin J. Lee

Date Considered

Sept. 5, 2003

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